

DLP472NP 0.47-Inch 1080p FHD Digital Micromirror Device

1 Features

- 0.47-inch diagonal micromirror array
 - 1080p FHD (1920 × 1080) display resolution
 - 5.4µm micromirror pitch
 - ±17° micromirror tilt (relative to the flat surface)
 - Bottom illumination
- SubLVDS input data bus
- Supports 1080p up to 240Hz
- Laser or LED operation supported by the DLPC8444 display controller and the DLPA3085 or DLPA3082 power management IC (PMIC) and LED driver

2 Applications

- Mobile smart TV
- Mobile projector
- Digital signage

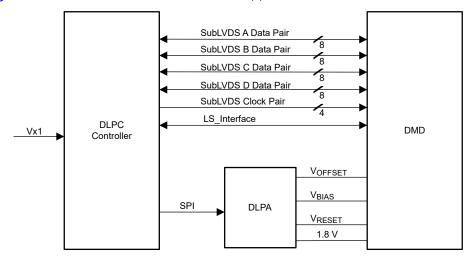
3 Description

The DLP472NP digital micromirror device (DMD) is a digitally controlled micro-electro-mechanical system (MEMS) spatial light modulator (SLM) that enables bright 1080p FHD display systems. The TI DLP® products 0.47-inch 1080p FHD chipset comprises the DLP472NP DMD, the DLPC8444 display controller, and the DLPA3085 or DLPA3082 PMIC and illuminator driver. The compact physical size of the chipset provides a complete system solution that enables small form factor 1080p FHD displays.

Device Information

PART NUMBER	PACKAGE ⁽¹⁾	PACKAGE SIZE
DLP472NP	FQY (166)	24.50mm × 11.00mm

For more information, see Section 12.



Simplified Application



Table of Contents

1 Features	
2 Applications	
3 Description	
4 Pin Configuration and Functions	3
4.1 Pin Functions	3
5 Specifications	7
5.1 Absolute Maximum Ratings	7
5.2 Storage Conditions	8
5.3 ESD Ratings	8
5.4 Recommended Operating Conditions	9
5.5 Thermal Information	11
5.6 Electrical Characteristics	11
5.7 Switching Characteristics	12
5.8 Timing Requirements	12
5.9 System Mounting Interface Loads	18
5.10 Micromirror Array Physical Characteristics	18
5.11 Micromirror Array Optical Characteristics	19
5.12 Window Characteristics	21
5.13 Chipset Component Usage Specification	21
6 Detailed Description	22
6.1 Overview	22
6.2 Functional Block Diagram	22
6.3 Feature Description	<mark>23</mark>
6.4 Device Functional Modes	<mark>23</mark>
6.5 Optical Interface and System Image Quality	
Considerations	23

6.6 Micromirror Array Temperature Calculation	. 24
6.7 Micromirror Power Density Calculation	.25
6.8 Micromirror Landed-On/Landed-Off Duty Cycle	. 27
7 Application and Implementation	
7.1 Application Information	
7.2 Typical Application	
7.3 Temperature Sensor Diode	
8 Power Supply Recommendations	
8.1 DMD Power Supply Power-Up Procedure	
8.2 DMD Power Supply Power-Down Procedure	
9 Layout	
9.1 Layout Guidelines	
9.2 Layout Example	
10 Device and Documentation Support	
10.1 Third-Party Products Disclaimer	
10.2 Device Support	
10.3 Documentation Support	. 37
10.4 Receiving Notification of Documentation Updates	.37
10.5 Trademarks	.37
10.6 Electrostatic Discharge Caution	.37
10.7 Glossary	
11 Revision History	. 37
12 Mechanical, Packaging, and Orderable	
Information	. 38



4 Pin Configuration and Functions

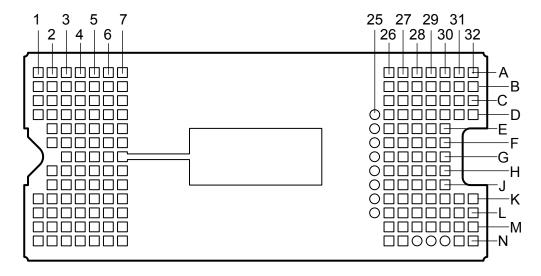


Figure 4-1. FQY Package 166-Pin LGA (Bottom View)

CAUTION

The layout and operation of signals identified in the *Pin Functions* table must be properly managed so that there is reliable operation of the 0.47" 1080p FHD S321 DMD. Refer to the *Layout Guidelines* for the DMD and controller before designing the board.

4.1 Pin Functions

PIN ⁽²⁾		(1)			TRACE	
NAME	PAD ID	TYPE ⁽¹⁾	DESCRIPTION	TERMINATION	LENGTH (mm)	
D_AP(0)	A2	I	High-speed Differential Data Pair lane A0	Differential 100Ω	3.75497	
D_AN(0)	B2	I	High-speed Differential Data Pair lane A0	Differential 100Ω	3.75482	
D_AP(1)	A6	I	High-speed Differential Data Pair lane A1	Differential 100Ω	4.62509	
D_AN(1)	B6	I	High-speed Differential Data Pair lane A1	Differential 100Ω	4.625	
D_AP(2)	C1	I	High-speed Differential Data Pair lane A2	Differential 100Ω	3.59503	
D_AN(2)	C2	I	High-speed Differential Data Pair lane A2	Differential 100Ω	3.59513	
D_AP(3)	C6	I	High-speed Differential Data Pair lane A3	Differential 100Ω	5.12758	
D_AN(3)	C7	I	High-speed Differential Data Pair lane A3	Differential 100Ω	5.12745	
D_AP(4)	G3	I	High-speed Differential Data Pair lane A4	Differential 100Ω	1.60057	
D_AN(4)	G4	I	High-speed Differential Data Pair lane A4	Differential 100Ω	1.6004	
D_AP(5)	F7	I	High-speed Differential Data Pair lane A5	Differential 100Ω	3.64067	
D_AN(5)	F6	I	High-speed Differential Data Pair lane A5	Differential 100Ω	3.64091	
D_AP(6)	F4	I	High-speed Differential Data Pair lane A6	Differential 100Ω	1.58206	
D_AN(6)	F5	I	High-speed Differential Data Pair lane A6	Differential 100Ω	1.58187	
D_AP(7)	H6	I	High-speed Differential Data Pair lane A7	Differential 100Ω	2.70067	
D_AN(7)	G6	I	High-speed Differential Data Pair lane A7	Differential 100Ω	2.70086	
DCLK_AP	E5	I	High-speed Differential Clock A	Differential 100Ω	2.96493	
DCLK_AN	D5	I	High-speed Differential Clock A	Differential 100Ω	2.9653	
D_BP(0)	B30	I	High-speed Differential Data Pair lane B0	Differential 100Ω	3.57087	
D_BN(0)	A30	I	High-speed Differential Data Pair lane B0	Differential 100Ω	3.57064	



PIN	2)	(1)			TRACE
NAME	PAD ID	TYPE ⁽¹⁾	DESCRIPTION	TERMINATION	LENGTH (mm)
D_BP(1)	C32	I	High-speed Differential Data Pair lane B1	Differential 100Ω	4.2546
D_BN(1)	B32	I	High-speed Differential Data Pair lane B1	Differential 100Ω	4.25425
D_BP(2)	A28	I	High-speed Differential Data Pair lane B2	Differential 100Ω	4.97968
D_BN(2)	B28	I	High-speed Differential Data Pair lane B2	Differential 100Ω	4.97953
D_BP(3)	C31	I	High-speed Differential Data Pair lane B3	Differential 100Ω	3.12736
D_BN(3)	C30	I	High-speed Differential Data Pair lane B3	Differential 100Ω	3.12743
D_BP(4)	C27	I	High-speed Differential Data Pair lane B4	Differential 100Ω	5.44353
D_BN(4)	B27	I	High-speed Differential Data Pair lane B4	Differential 100Ω	5.4433
D_BP(5)	D28	I	High-speed Differential Data Pair lane B5	Differential 100Ω	3.32124
D_BN(5)	D27	I	High-speed Differential Data Pair lane B5	Differential 100Ω	3.32115
D_BP(6)	F30	I	High-speed Differential Data Pair lane B6	Differential 100Ω	2.99334
D_BN(6)	E30	I	High-speed Differential Data Pair lane B6	Differential 100Ω	2.99374
D_BP(7)	G27	I	High-speed Differential Data Pair lane B7	Differential 100Ω	3.14865
D_BN(7)	G28	Į	High-speed Differential Data Pair lane B7	Differential 100Ω	3.14902
DCLK_BP	D29	I	High-speed Differential Clock B	Differential 100Ω	5.03976
DCLK_BN	D30	I	High-speed Differential Clock B	Differential 100Ω	5.0395
D_CP(0)	J4	I	High-speed Differential Data Pair lane C0	Differential 100Ω	2.06577
D_CN(0)	H4	I	High-speed Differential Data Pair lane C0	Differential 100Ω	2.06568
D_CP(1)	J7	I	High-speed Differential Data Pair lane C1	Differential 100Ω	4.87119
D_CN(1)	J6	I	High-speed Differential Data Pair lane C1	Differential 100Ω	4.87131
D_CP(2)	K5	I	High-speed Differential Data Pair lane C2	Differential 100Ω	4.69951
D_CN(2)	J5	I	High-speed Differential Data Pair lane C2	Differential 100Ω	4.69926
D_CP(3)	L4	I	High-speed Differential Data Pair lane C3	Differential 100Ω	3.27735
D_CN(3)	L5	I	High-speed Differential Data Pair lane C3	Differential 100Ω	3.27722
D_CP(4)	L2	Į	High-speed Differential Data Pair lane C4	Differential 100Ω	4.65167
D_CN(4)	M2	I	High-speed Differential Data Pair lane C4	Differential 100Ω	4.6513
D_CP(5)	M3	I	High-speed Differential Data Pair lane C5	Differential 100Ω	5.70359
D_CN(5)	N3	I	High-speed Differential Data Pair lane C5	Differential 100Ω	5.70352
D_CP(6)	M5	Į	High-speed Differential Data Pair lane C6	Differential 100Ω	2.57704
D_CN(6)	M6	I	High-speed Differential Data Pair lane C6	Differential 100Ω	2.57727
D_CP(7)	N7	I	High-speed Differential Data Pair lane C7	Differential 100Ω	3.77278
D_CN(7)	M7	Į.	High-speed Differential Data Pair lane C7	Differential 100Ω	3.77317
DCLK_CP	K2	I	High-speed Differential Clock C	Differential 100Ω	2.3747
DCLK_CN	J2	I	High-speed Differential Clock C	Differential 100Ω	2.37429
D_DP(0)	G29	I	High-speed Differential Data Pair lane D0	Differential 100Ω	3.67925
D_DN(0)	F29	Į	High-speed Differential Data Pair lane D0	Differential 100Ω	3.6794
D_DP(1)	F27	I	High-speed Differential Data Pair lane D1	Differential 100Ω	4.73751
D_DN(1)	E27	I	High-speed Differential Data Pair lane D1	Differential 100Ω	4.73796
D_DP(2)	K30	I	High-speed Differential Data Pair lane D2	Differential 100Ω	2.76933
D_DN(2)	K29	I	High-speed Differential Data Pair lane D2	Differential 100Ω	2.76936
D_DP(3)	J27	I	High-speed Differential Data Pair lane D3	Differential 100Ω	3.07794
D_DN(3)	K27	I	High-speed Differential Data Pair lane D3	Differential 100Ω	3.07804
D_DP(4)	M30	I	High-speed Differential Data Pair lane D4	Differential 100Ω	3.60026
D_DN(4)	L30	1	High-speed Differential Data Pair lane D4	Differential 100Ω	3.60028



PIN⁽²⁾ **TRACE** TYPE(1) DESCRIPTION LENGTH **TERMINATION** NAME PAD ID (mm) D_DP(5) M27 h High-speed Differential Data Pair lane D5 Differential 100Ω 3.24012 D DN(5) L27 High-speed Differential Data Pair lane D5 Differential 100Ω 3.24002 D DP(6) N26 High-speed Differential Data Pair lane D6 Differential 100Ω 4.69564 M26 Differential 100Ω D_DN(6) High-speed Differential Data Pair lane D6 4.69594 D_DP(7) M31 High-speed Differential Data Pair lane D7 Differential 100Ω 3.97347 High-speed Differential Data Pair lane D7 D DN(7) M32 Differential 100Ω 3.97352 DCLK_DP H29 High-speed Differential Clock D Differential 100Ω 1.7593 DCLK DN J29 ı High-speed Differential Clock D Differential 100Ω 1.75933 LS WDATA D4 ı LVDS Data 2.29224 LS CLK C4 LVDS CLK 1.73951 C5 0 LS RDATA A LVCMOS Output 2.72344 0 LS RDATA B D3 LVCMOS Output 2.22814 **E**3 0 LS RDATA C LVCMOS Output 3.22863 LS RDATA D F3 0 LVCMOS Output 4.90151 DMD_DEN_ARSTZ D2 ARSTZ 1.80911 TEMP_N N1 Temp Diode N 1.84006 TEMP P M1 Temp Diode P 2.62822 A3, A4, C26, D1, D6, D7, D26, E2, E6, E7, E26, F2, VDD 14.26561 G30, H28, Digital Core Supply Voltage H30, J26, J30, K1, K6, K26, K31, K32, L1, L31, L32, N2 A5. B5. F26, G26, VDDI Р SubLVDS supply voltage 3.72532 H26, H27, K7, L7 Supply voltage for negative bias of VRESET B3, B26 Р 25.57603 micromirror reset signal Supply voltage for positive bias of **VBIAS** A27. B4 Ρ 24.70004 micromirror reset signal Supply voltage for HVCMOS logic, stepped A26, C3, Р VOFFSET 8.73417 L6, L26 up logic level



PIN ⁽²⁾		(4)			TRACE
NAME	PAD ID	TYPE ⁽¹⁾	DESCRIPTION	TERMINATION	LENGTH (mm)
VSS	A1, A7, A29, A31, A32, B1, B7, B29, B31, C28, C29, D31, D32, E4, E28, E29, F28, G5, G7, H2, H3, H5, H7, J3, J28, K3, K4, K28, L3, L28, L29, M4, M28, M29, N4, N5, N6, N27, N31, N32	G	Ground		24.6246
N/C	N28, N29, N30, L25, K25, J25, H25, G25, F25, E25, D25	NC	No Connect Pin		None

I=Input, O=Output, P=Power, G=Ground, NC=No Connect Only 163 pins are electrically connected for functional use.



5 Specifications

5.1 Absolute Maximum Ratings

Operation outside the Absolute Maximum Ratings may cause permanent device damage. Absolute Maximum Ratings do not imply functional operation of the device at these or any other conditions beyond those listed under Recommended Operating Conditions. If outside the Recommended Operating Conditions but within the Absolute Maximum Ratings, the device may not be fully functional, and this may affect device reliability, functionality, performance, and shorten the device lifetime.

		MIN	MAX	UNIT
SUPPLY VOLTAGE			•	
V_{DD}	Supply voltage for LVCMOS core logic and LPSDR low speed interface (1)	-0.5	2.3	V
V_{DDI}	Supply voltage for SubLVDS receivers ⁽¹⁾	-0.5	2.3	V
V _{OFFSET}	Supply voltage for HVCMOS and micromirror electrode ⁽¹⁾ (2)	-0.5	11	V
V _{BIAS}	Supply voltage for micromirror electrode ⁽¹⁾	-0.5	19	V
V _{RESET}	Supply voltage for micromirror electrode ⁽¹⁾	-15	0.5	V
V _{DDI} - V _{DD}	Supply voltage delta, absolute value ⁽³⁾		0.3	V
V _{BIAS} - V _{OFFSET}	Supply voltage delta, absolute value ⁽⁴⁾		11	V
V _{BIAS} - V _{RESET}	Supply voltage delta, absolute value ⁽⁵⁾		34	V
INPUT VOLTAGE			1	
	Input voltage for other inputs—LSIF and LVCMOS ⁽¹⁾	-0.5	V _{DD} + 0.5	V
	Input voltage for other inputs—SubLVDS ^{(1) (6)}	-0.5	V _{DDI} + 0.5	V
SUBLVDS INTERFACE			'	
V _{ID}	SubLVDS input differential voltage (absolute value) ^{(1) (6)}		810	mV
I _{ID}	SubLVDS input differential current		10	mA
CLOCK FREQUENCY			'	
f_{clock}	Clock frequency for low-speed interface LS_CLK	100	130	MHz
TEMPERATURE DIODE			'	
I _{TEMP_DIODE}	Max current source into the temperature diode		120	μA
ENVIRONMENTAL			1	
T	Temperature, operating ⁽⁷⁾	0	90	°C
T_{WINDOW} and T_{ARRAY}	Temperature, non-operating ⁽⁷⁾	-40	90	°C
T _{DELTA}	Absolute temperature delta between any point on the window edge and the ceramic test point TP1 ⁽⁸⁾		30	°C
T _{DP}	Dew point temperature, operating and non-operating (noncondensing)		81	°C

- (1) All voltage values are for the ground terminals (V_{SS}). The following required power supplies must be connected for proper DMD operation: V_{DD}, V_{DDI}, V_{OFFSET}, V_{BIAS}, and V_{RESET}. All V_{SS} connections are also required.
- (2) V_{OEESET} supply transients must fall within specified voltages.
- (3) Exceeding the recommended allowable absolute voltage difference between V_{DDI} and V_{DD} may result in excessive current draw and permanent damage to the device.
- (4) Exceeding the recommended allowable absolute voltage difference between V_{BIAS} and V_{OFFSET} may result in excessive current draw and permanent damage to the device.
- (5) Exceeding the recommended allowable absolute voltage difference between V_{BIAS} and V_{RESET} may result in excessive current draw and permanent damage to the device.
- (6) This maximum input voltage rating applies when each input of a differential pair is at the same voltage potential. Sub-LVDS differential inputs must not exceed the specified limit, or damage may result to the internal termination resistors.
- (7) The highest temperature of the active array (as calculated in Section 6.6) or of any point along the window edge as defined in Figure 6-1. The locations of thermal test points TP2, TP3, TP4, and TP5 in Figure 6-1 are intended to measure the highest window edge temperature. If a particular application causes another point on the window edge to be at a higher temperature, that point should be used.
- (8) The temperature delta is the highest difference between the ceramic test point 1 (TP1) and anywhere on the window edge, as shown in Figure 6-1. The window test points TP2, TP3, TP4, and TP5 shown in Figure 6-1 are intended to result in the worst-case delta. If a particular application causes another point on the window edge to result in a larger delta temperature, that point should be used.



5.2 Storage Conditions

Applicable for the DMD as a component or non-operating in a system.

		MIN	MAX	UNIT
T _{DMD}	DMD temperature	-40	85	°C
T _{DP-AVG}	Average dew point temperature, non-condensing ⁽¹⁾		24	°C
T _{DP-ELR}	Elevated dew point temperature range, non-condensing ⁽²⁾	28	36	°C
CT _{ELR}	Cumulative time in elevated dew pointt temperature range		6	months

- (1) The average temperature over time (including storage and operating temperatures) that the device is not in the elevated dew point temperature range.
- (2) Exposure to dew point temperatures in the elevated range during storage and operation should be limited to less than a total cumulative time of CT_{ELR}.

5.3 ESD Ratings

			VALUE	UNIT
	Human body model (HBM), per ANSI/ESDA/JEDEC JS-001 ⁽¹⁾	±1000	V	
V _(ESD)	Discharge	Charged device model (CDM), per JEDEC specification ANSI/ESDA/JEDEC JS-002 ⁽²⁾	±250	V

- (1) JEDEC document JEP155 states that 500V HBM allows safe manufacturing with a standard ESD control process.
- (2) JEDEC document JEP157 states that 250V CDM allows safe manufacturing with a standard ESD control process.



5.4 Recommended Operating Conditions

Over operating free-air temperature range and supply voltages (unless otherwise noted). The functional performance of the device specified in this data sheet is achieved when operating the device within the limits defined by the Recommended Operating Conditions. No level of performance is implied when operating the device above or below the Recommended Operating Conditions limits.

		MIN	TYP	MAX	UNIT
SUPPLY VOLTAGE	RANGE				
VDD	Supply voltage for LVCMOS core logic ⁽¹⁾ (2) Supply voltage for LPSDR low-speed interface ⁽¹⁾ (2)	1.71	1.8	1.95	V
VDDI	Supply voltage for SubLVDS receivers ^{(1) (2)}	1.71	1.8	1.95	V
VOFFSET	Supply voltage for HVCMOS and micromirror electrode ⁽¹⁾ (2) (3)	9.5	10	10.5	V
VBIAS	Supply voltage for mirror electrode ⁽¹⁾ (2)	17.5	18	18.5	V
VRESET	Supply voltage for micromirror electrode ⁽¹⁾ (2)	-14.5	-14	-13.5	V
VDDI- VDD	Supply voltage delta (absolute value) ^{(1) (2) (4)}			0.3	V
VBIAS-VOFFSET	Supply voltage delta (absolute value) ⁽¹⁾ (2) (5)			10.5	V
VBIAS- VRESET	Supply voltage delta (absolute value) ⁽¹⁾ (2) (6)			33	V
CLOCK FREQUENC	CY				
,	Clock frequency for low speed interface LS_CLK ⁽⁷⁾	108		120	MHz
f clock	Clock frequency for high-speed interface DCLK (8)			720	MHz
DCD _{IN}	Duty cycle distortion	48		52	%
SUBLVDS INTERFA	CE				
V _{ID}	LVDS differential input voltage magnitude ⁽⁸⁾	150	250	350	mV
V _{CM}	Common mode voltage ⁽⁸⁾	700	900	1100	mV
V _{SUBLVDS}	SubLVDS voltage ⁽⁸⁾	525		1275	mV
Z _{LINE}	Line differential impedance (PWB/trace)	90	100	110	Ω
Z _{IN}	Internal differential termination resistance ⁽¹⁰⁾	80	100	120	Ω
	100Ω differential PCB trace	6.35		152.4	mm
ENVIRONMENTAL					
_	Array temperature, long-term operation ⁽⁹⁾ (10) (11) (12)	10		40 to 70	°C
T _{ARRAY}	Array temperature, short-term operation, 500 hr max ⁽¹⁰⁾ (13)	0		10	°C
T _{Window}	Window temperature, operational ⁽¹⁴⁾			85	°C
T _{DELTA}	Absolute Temperature difference between any point on the window edge and the ceramic test point TP1 ⁽¹⁵⁾			15	°C
T _{DP-AVG}	Average dew point temperature, (non-condensing) ⁽¹⁶⁾			24	°C
T _{DP-ELR}	Elevated dew point temperature range, (non-condensing) ⁽¹⁷⁾		28	36	°C
CT _{ELR}	Cumulative time in elevated dew point temperature range			6	Months
ILLUMINATION					
ILL _{UV}	Illumination, wavelength < 410nm ⁽⁹⁾			10	mW/cm ²
ILL _{VIS}	Illumination power at wavelengths ≥ 410nm and ≤ 800nm ⁽¹⁸⁾	-		20.5	W/cm ²
ILL _{IR}	Illumination, wavelength between > 800nm			10	mW/cm ²
ILL _{BLU}	Illumination power at wavelengths ≥ 410nm and ≤ 475nm ⁽¹⁸⁾			6.5	W/cm ²
ILL _{BLU1}	Illumination power at wavelengths ≥ 410nm and ≤ 445nm ⁽¹⁸⁾			1.2	W/cm ²
ILL _θ	Illumination marginal ray angle ⁽¹⁹⁾			55	deg

⁽¹⁾ The following power supplies are all required to operate the DMD: V_{DD}, V_{DDI}, V_{OFFSET}, V_{BIAS}, and V_{RESET}. All V_{SS} connections are required to operate the DMD.

⁽²⁾ All voltage values are with respect to the V_{SS} ground pins.

⁽³⁾ V_{OFFSET} supply transients must fall within specified max voltages.

⁽⁴⁾ To prevent excess current, the supply voltage delta $|V_{DDI} - V_{DD}|$ must be less than the specified limit.

To prevent excess current, the supply voltage delta |V_{BIAS} - V_{OFFSET}| must be less than the specified limit.

- (6) To prevent excess current, the supply voltage delta |VBIAS VRESET| must be less than the specified limit.
- (7) LS_CLK must run as specified to ensure internal DMD timing for reset waveform commands.
- (8) Refer to the SubLVDS timing requirements in Section 5.8.
- (9) Simultaneous exposure of the DMD to the maximum Recommended Operating Conditions for temperature and UV illumination will reduce device lifetime.
- (10) The array temperature cannot be measured directly and must be computed analytically from the temperature measured at test point (TP1), as shown in Figure 6-1 and the package thermal resistance using Section 6.6.
- (11) Per Maximum Recommended Array Temperature—Derating Curve, the maximum operational array temperature should be derated based on the micromirror landed duty cycle that the DMD experiences in the end application. Refer to Micromirror Landed-On/Landed-Off Duty Cycle for a definition of micromirror landed duty cycle.
- (12) Long-term is defined as the usable life of the device.
- (13) Short-term is the total cumulative time over the useful life of the device.
- (14) Window temperature is the highest temperature on the window edge. The locations of thermal test points TP2, TP3, TP4, and TP5 in Figure 6-1 are intended to measure the highest window edge temperature. If a particular application causes another point on the window edge to be at a higher temperature, that point should be used.
- (15) Temperature delta is the highest difference between the ceramic test point 1 (TP1) and anywhere on the window edge shown in Figure 6-1. The window test points TP2, TP3, TP4, and TP5 shown in Figure 6-1 are intended to result in the worst case delta temperature. If a particular application causes another point on the window edge to result in a larger delta temperature, that point should be used.
- (16) The average over time (including storage and operating) that the device is not in the 'elevated dew point temperature range'.
- (17) Exposure to dew point temperatures in the elevated range during storage and operation should be limited to less than a total cumulative time of CT_{FLR}.
- (18) The maximum allowable optical power incident on the DMD is limited by the maximum optical power density for each wavelength range specified and the micromirror array temperature (T_{ARRAY}).
- (19) The maximum marginal ray angle of the incoming illumination light at any point in the micromirror array, including Pond of Micromirrors (POM), should not exceed 55 degrees from the normal to the device array plane. The device window aperture has not necessarily been designed to allow incoming light at higher maximum angles to pass to the micromirrors, and the device performance has not been tested or qualified at angles exceeding this. Illumination light exceeding this angle outside the micromirror array (including POM) will contribute to thermal limitations described in this document, and may negatively affect the lifetime.

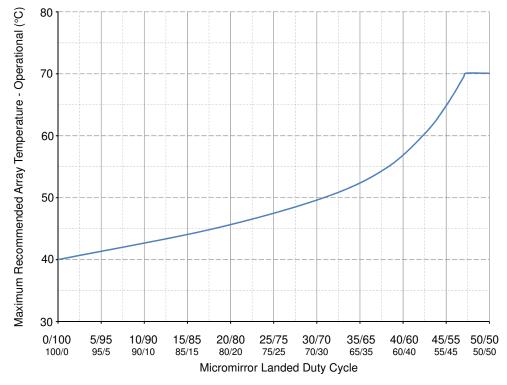


Figure 5-1. Maximum Recommended Array Temperature—Derating Curve

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5.5 Thermal Information

THERMAL METRIC	DLP472NP FQY 163 PIN	UNIT		
THERMAL INFORMATION				
Thermal Resistance, active area to test point 1 (TP1) ⁽¹⁾	1.2	°C/W		

⁽¹⁾ The DMD is designed to conduct absorbed and dissipated heat to the back of the package. The cooling system must be capable of maintaining the DMD within the temperature range specified in the Recommended Operating Conditions. The total heat load on the DMD is largely driven by the incident light absorbed by the active area; although other contributions include light energy absorbed by the window aperture and electrical power dissipation of the array. Optical systems should be designed to minimize the light energy falling outside the window's clear aperture since any additional thermal load in this area can significantly degrade the reliability of the device.

5.6 Electrical Characteristics

Over operating free-air temperature range (unless otherwise noted) (1)

	PARAMETER ⁽⁷⁾	TEST CONDITIONS (2)	MIN	TYP MAX	UNIT
CURRENT					
I _{DD}	Supply current: V _{DD} ^{(3) (4)}	Typical		140	mA
I _{DDI}	Supply current: V _{DDI} ^{(3) (4)}	Typical		45	mA
I _{OFFSET}	Supply current: V _{OFFSET} (5) (6)	Typical		6	mA
I _{BIAS}	Supply current: V _{BIAS} (5) (6)	Typical		.5	mA
I _{RESET}	Supply current: V _{RESET} (6)	Typical	-1.8		mA
POWER					
P _{DD}	Supply power dissipation: V _{DD} ^{(3) (4)}	Typical		252	mW
P _{DDI}	Supply power dissipation: V _{DDI} ^{(3) (4)}	Typical		81	mW
P _{OFFSET}	Supply power dissipation: V _{OFFSET} (5) (6)	Typical		60	mW
P _{BIAS}	Supply power dissipation: V _{BIAS} ^{(5) (6)}	Typical		9	mW
P _{RESET}	Supply power dissipation: V _{RESET} ⁽⁶⁾	Typical		25.2	mW
P _{TOTAL}	Supply power dissipation Total	Typical		427.2	mW
LPSDR INPU	г		<u>'</u>		
V _{IH}	High-level input voltage ⁽⁸⁾ (9)		0.7 x V _{DD}	V _{DD} + 0.3	x VDD
V _{IL}	Low-level input voltage ^{(8) (9)}		-0.3	0.3 x V _{DD}	x VDD
V _{IH(AC)}	AC input high voltage ^{(8) (9)}		0.8 × V _{DD}	V _{DD} + 0.3	x VDD
V _{IL(AC)}	AC input low voltage ⁽⁸⁾ (9)		-0.3	0.2 × V _{DD}	x VDD
VHyst	Input Hysteresis (V _{T+} – V _{T-})		0.1 × V _{DD}	0.4 × V _{DD}	V
I _{IL}	Low level input current	V _{DD} = 1.95V, V _I = 0V	-100		nA
I _{IH}	High level input current	V _{DD} = 1.95V, V _I = 1.95V		135	uA
LPSDR OUTP	PUT		•		•
V _{OH}	DC output high voltage ⁽¹⁰⁾	I _{OH} = -2mA	0.8 x V _{DD}		X VDD
V _{OL}	DC output low voltage ⁽¹⁰⁾	I _{OL} = 2mA		0.2 x V _{DD}	X VDD
CAPACTIANO	E				
C _{IN}	Input capacitance LVCMOS	F = 1MHz		10	pF
C _{IN}	Input capacitance SubLVDS	F = 1MHz		20	pF
C _{OUT}	Output capacitance	F = 1MHz		10	pF

⁽¹⁾ Device electrical characteristics are over Section 5.4 unless otherwise noted.

²⁾ All voltage values are with respect to the ground pins (V_{SS}).



- To prevent excess current, the supply voltage delta | V_{DDI} V_{DD} | must be less than the specified limit.
- Supply power dissipation based on non-compressed commands and data. (4)
- To prevent excess current, the supply voltage delta | V_{BIAS} V_{OFFSET} | must be less than the specified limit. (5)
- Supply power dissipation based on three global resets in 200µs.
- All power supply connections are required to operate the DMD: V_{DD}, V_{DDI}, V_{OFFSET}, V_{BIAS}, V_{RESET}. All V_{SS} connections are also (7) required.
- (8) LPSDR specifications are for pins LS CLK and LS WDATA.
- The low-speed interface is LPSDR and adheres to the Electrical Characteristics and AC/DC Operating Conditions table in JEDEC Standard No. 209B, Low-Power Double Data Rate (LPDDR) JESD209B.
- (10) LPSDR output specification is for pins LS_RDATA_A, LS_RDATA_B, LS_RDATA_C, LS_RDATA_D.

5.7 Switching Characteristics

Over operating free-air temperature range (unless otherwise noted)(1)

	PARAMETER	TEST CONDITIONS	MIN	TYP	MAX	UNIT
t _{PD}	Output propagation, clock to Q, rising edge of LS_CLK input to LS_RDATA output.	C _L = 45pF			15	ns
	Slew rate, LS_RDATA		0.3			V/ns
	Output duty cycle distortion, LS_RDATA		40		60	%

(1) Device electrical characteristics are over Section 5.4 unless otherwise noted.

5.8 Timing Requirements

Over operating free-air temperature range (unless otherwise noted) (1)

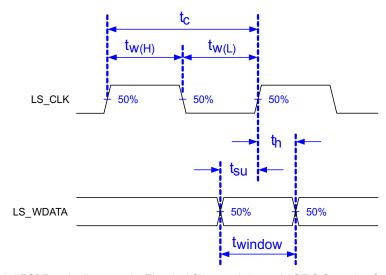
			MIN	NOM	MAX	UNIT
LPSDR						
t _f	Fall slew rate (2)	(80% to 20%) × V _{DD} ⁽⁵⁾	0.25			V/ns
t _c	Cycle time LS_CLK ⁽⁵⁾	50% to 50% reference points ⁽⁵⁾	7.7	8.3		ns
t _r	Rise slew rate (1)	(30% to 80%) × V _{DD} ⁽⁶⁾	1		3	V/ns
t _f	Fall slew rate (1)	(70% to 20%) x V _{DD} ⁽⁶⁾	1		3	V/ns
t _r	Rise slew rate (2)	(20% to 80%) × V _{DD} ⁽⁶⁾	0.25			V/ns
t _{W(H)}	Pulse duration LS_CLK high	50% to 50% reference points ⁽⁵⁾	3.1			ns
t _{W(L)}	Pulse duration LS_CLK low	50% to 50% reference points ⁽⁵⁾	3.1			ns
t _{WINDOW}	Window time ⁽¹⁾ (3)	Setup time + Hold time ⁽⁵⁾	3			ns
t _{DERATING}	Window time derating ^{(1) (3)}	For each 0.25V/ns reduction in slew rate below 1 V/ ns ⁽⁸⁾		0.35		ns
t _{su}	Setup time	LS_WDATA valid before LS_CLK ⁽⁵⁾			1.5	ns
t _h	Hold time	LS_WDATA valid after LS_CLK ⁽⁵⁾			1.5	ns
SubLVDS						
t _r	Rise slew rate	20% to 80% reference points ⁽⁷⁾	0.7	1		V/ns
t _f	Fall slew rate	80% to 20% reference points ⁽⁷⁾	0.7	1		V/ns
t _c	Cycle time D_CLK ⁽⁹⁾	50% to 50% reference points ⁽⁹⁾	1.35	1.39		ns
t _{W(H)}	Pulse duration DCLK high	50% to 50% reference points ⁽⁹⁾	0.7			ns
t _{W(L)}	Pulse duration DCLK low	50% to 50% reference points ⁽⁹⁾	0.7			ns
t _{su}	Setup time	DATA valid before D_CLK ⁽⁹⁾			0.17	ns
t _h	Hold time	DATA valid after D_CLK ⁽⁹⁾			0.17	ns
t _{WINDOW}	Window time	Setup time + Hold time ⁽⁹⁾ (10)			0.25	ns
t _{POWER}	Power-up receiver ⁽⁴⁾				200	ns

- Specification is for LS CLK and LS WDATA pins. Refer to the LPSDR input rise and fall slew rate in Figure 5-3.
- Specification is for the DMD DEN ARSTZ pin. Refer to the LPSDR input rise and fall slew rate in Figure 5-3. (2)
- (3) Window time derating example: 0.5V/ns slew rate increases the window time by 0.7ns, from 3ns to 3.7ns.
- The specification is for SubLVDS receiver time only and does not take into account commanding and latency after commanding. (4)

(5) See Figure 5-2.

- See Figure 5-3. (6)
- See Figure 5-4. (7)
- (8) See Figure 5-5.
- (9) See Figure 5-6.





The low-speed interface is LPSDR and adheres to the Electrical Characteristics and AC/DC Operating Conditions table in JEDEC Standard No. 209B, Low Power Double Data Rate (LPDDR) JESD209B.



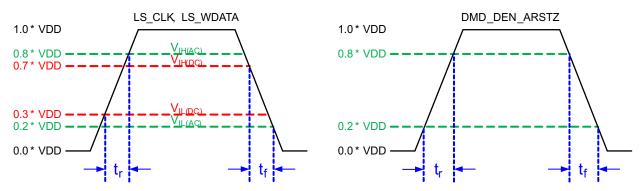


Figure 5-3. LPSDR Input Rise and Fall Slew Rate



Not to Scale

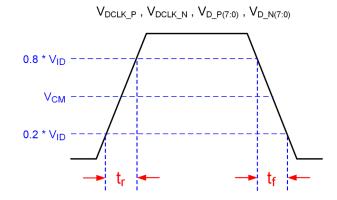
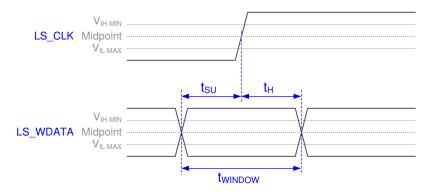


Figure 5-4. SubLVDS Input Rise and Fall Slew Rate



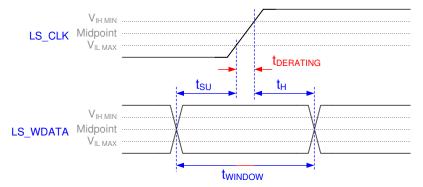


Figure 5-5. Window Time Derating Concept

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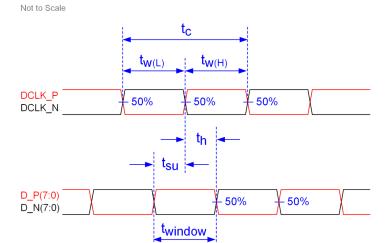
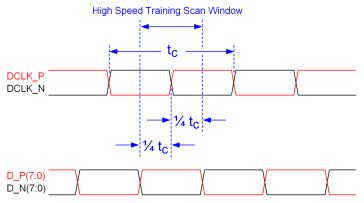


Figure 5-6. SubLVDS Switching Parameters



Note: Refer to Section 5.8 for details.

Figure 5-7. High-Speed Training Scan Window

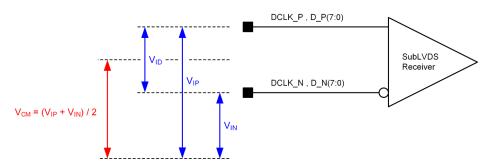


Figure 5-8. SubLVDS Voltage Parameters



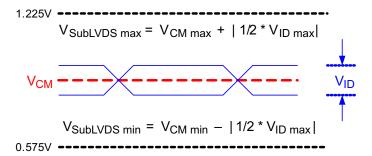


Figure 5-9. SubLVDS Waveform Parameters

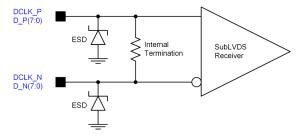


Figure 5-10. SubLVDS Equivalent Input Circuit

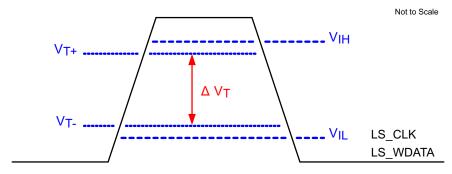


Figure 5-11. LPSDR Input Hysteresis

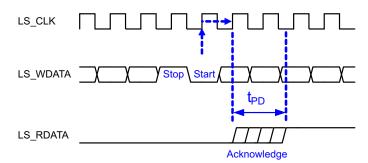
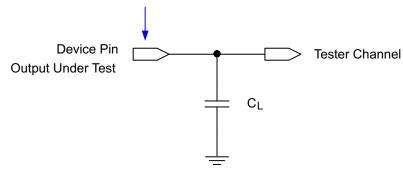


Figure 5-12. LPSDR Read Out

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Data Sheet Timing Reference Point



See Section 5.6 for more information.

Figure 5-13. Test Load Circuit for Output Propagation Measurement



5.9 System Mounting Interface Loads

PARAMETER	CONDITION	MIN	NOM	MAX	UNIT
Thermal Interface Area	Maximum load evenly distributed within each area (1)			73.5	N
Electrical Interface Area	Maximum load evenly distributed within each area (1)			150	IN

(1) See Figure 5-14.

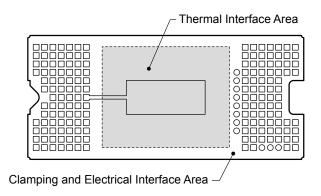


Figure 5-14. System Mounting Interface Loads

5.10 Micromirror Array Physical Characteristics

PAF	PARAMETER DESCRIPTION		
Number of active columns (1)	M	1920	micromirrors
Number of active rows (1)	N	1080	micromirrors
Micromirror (pixel) pitch (1)	P	5.4	μm
Micromirror active array width (1)	Micromirror pitch × number of active columns	10.368	mm
Micromirror active array height (1)	Micromirror pitch × number of active columns	5.832	mm
Micromirror active border (2)	Pond of micromirror (POM)	20	micromirrors/side

- (1) See Figure 5-15.
- (2) The structure and qualities of the borders around the active array includes a band of partially functional micromirrors referred to as the Pond of Micromirrors (POM). These micromirrors are structurally and/or electrically prevented from tilting toward the bright or ON state but still require an electrical bias to tilt toward the OFF state.



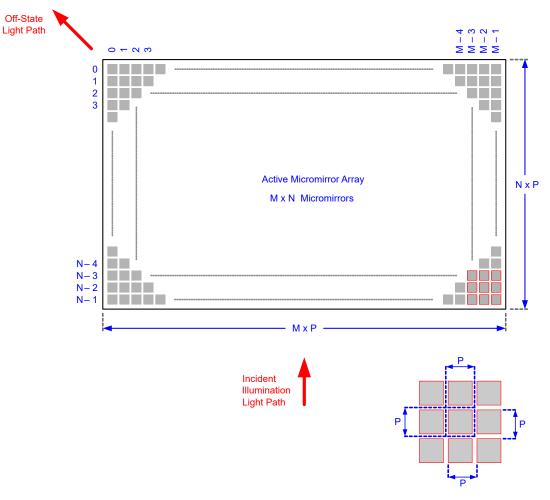


Figure 5-15. Micromirror Array Physical Characteristics

5.11 Micromirror Array Optical Characteristics

	PARAMETER		MIN TY	P MAX	UNIT
Micromirror tilt ang	Micromirror tilt angle		1	7	۰
Micromirror tilt ang	le tolerance (2) (3) (4) (5)		-1.4	1.4	۰
Micromirror tilt dire	ection ^{(6) (7)}	Landed ON state	27	0	۰
Micromirror tilt dire	Micromirror tilt direction (6) (7)		18	0	٥
Micromirror crossover time (8)		Typical Performance		1 3	110
Micromirror switch	ing time ⁽⁹⁾	Typical Performance	6		· μs
	Bright pixel(s) in active area (11)	Gray 10 Screen (12)		0	
	Bright pixel(s) in the POM (13)	Gray 10 Screen (12)		1	
Image Performance (10)	Dark pixel(s) in the active area (14)	White Screen		4	micromirrors
	Adjacent pixel(s) (15)	Any Screen		0	
	Unstable pixel(s) in active area (16)	Any Screen		0	

- (1) Measured relative to the plane formed by the overall micromirror array.
- (2) Additional variation exists between the micromirror array and the package datums.
- (3) Represents the landed tilt angle variation relative to the nominal landed tilt angle.
- (4) Represents the variation that can occur between any two individual micromirrors, located on the same device or located on different devices.
- (5) For some applications, it is critical to account for the micromirror tilt angle variation in the overall system optical design. With some system optical designs, the micromirror tilt angle variation within a device may result in perceivable non-uniformities in the light field



reflected from the micromirror array. With some system optical designs, the micromirror tilt angle variation between devices may result in colorimetry variations, system efficiency variations, or system contrast variations.

- (6) When the micromirror array is landed (not parked), the tilt direction of each individual micromirror is dictated by the binary contents of the CMOS memory cell associated with each individual micromirror. A binary value of 1 results in a micromirror landing in the ON State direction. A binary value of 0 results in a micromirror landing in the OFF State direction. See the Micromirror Landed Orientation and Tilt Figure 5-16.
- (7) Micromirror tilt direction is measured as in a typical polar coordinate system: Measuring counter-clockwise from a 0° reference, which is aligned with the +X Cartesian axis.
- (8) The time required for a micromirror to nominally transition from one landed state to the opposite landed state.
- (9) The minimum time between successive transitions of a micromirror.
- (10) Conditions of acceptance: All DMD image quality returns will be evaluated using the following projected image test conditions: Test set degamma shall be linear

Test set brightness and contrast shall be set to nominal

The diagonal size of the projected image shall be a minimum of 20 inches

The projections screen shall be 1X gain

The projected image shall be inspected from a 38-inch minimum viewing distance

The image must be in focus during all image quality tests.

- (11) Bright pixel definition: A single pixel or mirror that is stuck in the ON position and is visibly brighter than the surrounding pixels
- (12) Gray 10 screen definition: All areas of the screen are colored with the following settings:

Red = 10/255

Green = 10/255

Blue = 10/255

- (13) POM definition: Rectangular border of off-state mirrors surrounding the active area
- (14) Dark pixel definition: A single pixel or mirror that is stuck in the OFF position and is visibly darker than the surrounding pixels
- (15) Adjacent pixel definition: Two or more stuck pixels sharing a common border or common point, also referred to as a cluster
- (16) Unstable pixel definition: A single pixel or mirror that does not operate in sequence with parameters loaded into memory. The unstable pixel appears to be flickering asynchronously with the image

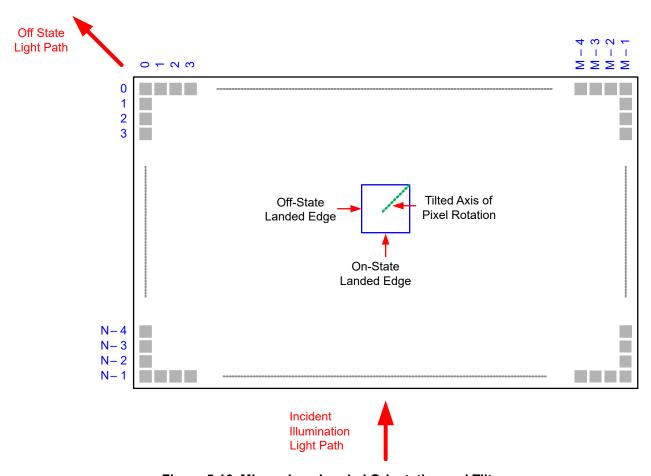


Figure 5-16. Micromirror Landed Orientation and Tilt



5.12 Window Characteristics

	DESCRIPTION ⁽¹⁾	MIN	TYP	MAX
Window material			Corning Eagle XG	
Window refractive index	At wavelength 546.1nm		1.5119	
Window aperture ⁽²⁾			See ⁽²⁾ .	
Illumination overfill ⁽³⁾			See ⁽³⁾ .	
Window transmittance, single-pass	Minimum within the wavelength range 420nm to 680nm. Applies to all angles 0° to 30° AOI. (4)	97%		
through both surfaces and glass	Average over the wavelength range 420nm to 680 nm. Applies to all angles 30° to 45° AOI. (4)	97%		

- (1) See Section 6.5
- (2) See the package mechanical characteristics for details regarding the size and location of the window aperture.
- (3) The active area of the DMD device is surrounded by an aperture on the inside of the window surface that masks structures of the DMD device assembly from normal view. The aperture is sized to anticipate several optical conditions. Overfill light illuminating the area outside the active array can scatter and create adverse effects on the performance of an end application using the DMD. The illumination optical system should be designed to limit the light flux incident outside the active array to less than 10% of the average flux level in the active area. Depending on the particular system's optical architecture and assembly tolerances, the amount of overfill light on the outside of the active array may cause system performance degradation.
- (4) Angle of incidence (AOI) is the angle between an incident ray and the normal to a reflecting or refracting surface.

5.13 Chipset Component Usage Specification

Reliable function and operation of the DLP472NP DMD requires that it be used in conjunction with the other components of the applicable DLP chipset, including those components that contain or implement TI DMD control technology. TI DMD control technology consists of the TI technology and devices used for operating or controlling a DLP DMD.

Note

TI assumes no responsibility for image quality artifacts or DMD failures caused by optical system operating conditions exceeding limits described previously.

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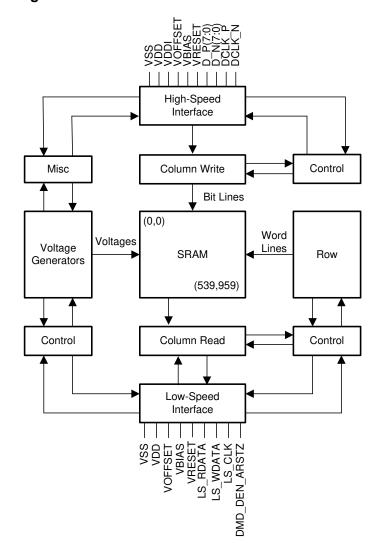
6 Detailed Description

6.1 Overview

The DLP472NP DMD is a 0.47-inch diagonal spatial light modulator that consists of an array of highly reflective aluminum micromirrors. The DMD is an electrical input, optical output micro-optical-electrical-mechanical system (MOEMS). The electrical interface is low-voltage differential signaling (LVDS). The DMD consists of a two-dimensional array of 1-bit CMOS memory cells. The array is organized in a grid of M memory cell columns by N memory cell rows. Refer to the Functional Block Diagram. The positive or negative deflection angle of the micromirrors can be individually controlled by changing the address voltage of underlying CMOS addressing circuitry and micromirror reset signals (MBRST).

The DLP 0.47" 1080p FHD chipset is comprised of the DLP472NP DMD, DLPC8444 display controller, and the DLPA3085 or DLPA3082 PMIC driver. To ensure reliable operation, the DLP472NP DMD must always be used with the DLP display controller and the PMIC specified in the chipset.

6.2 Functional Block Diagram



6.3 Feature Description

6.3.1 Power Interface

The DMD requires 4 DC voltages: 1.8V source, V_{OFFSET} , V_{RESET} , and V_{BIAS} . In a typical LED-based system, 1.8V, V_{OFFSET} , V_{RESET} , and V_{BIAS} is managed by the DLPA3085 or DLPA3082 PMIC and LED driver.

6.3.2 LPSDR Low-Speed Interface

The Low Speed Interface handles instructions that configure the DMD and control reset operation. LS_CLK is the low-speed clock, and LS_WDATA is the low speed data input.

6.3.3 High-Speed Interface

The purpose of the high-speed interface is to transfer pixel data rapidly and efficiently, making use of high-speed DDR transfer and compression techniques to save power and time. The high-speed interface contains differential SubLVDS receivers for inputs, with a dedicated clock.

6.3.4 Timing

The data sheet provides timing at the device pin. For output timing analysis, the tester pin electronics and its transmission line effects must be considered. Figure 5-13 shows an equivalent test load circuit for the output under test. Timing reference loads are not intended to be precise representations of any particular system environment or depiction of the actual load presented by a production test. System designers should use IBIS or other simulation tools to correlate the timing reference load to a system environment. The load capacitance value stated is only for characterization and measurement of AC timing signals. This load capacitance value does not indicate the maximum load the device is capable of driving.

6.4 Device Functional Modes

DMD functional modes are controlled by the DLPC8444 display controller. See the DLPC8444 display controller data sheet or contact a TI applications engineer.

6.5 Optical Interface and System Image Quality Considerations

TI assumes no responsibility for end-equipment optical performance. Achieving the desired end-equipment optical performance involves making trade-offs between numerous component and system design parameters. Optimizing system optical performance and image quality strongly relate to optical system design parameter trades. Although it is not possible to anticipate every conceivable application, projector image quality and optical performance are contingent on compliance with the optical system operating conditions described in the following sections.

6.5.1 Numerical Aperture and Stray Light Control

The angle defined by the numerical aperture of the illumination and projection optics at the DMD optical area should be the same. This angle should not exceed the nominal device micromirror tilt angle unless appropriate apertures are added in the illumination and projection pupils to block out flat-state and stray light from the projection lens. The micromirror tilt angle defines the DMD's capability to separate the "ON" optical path from any other light path, including undesirable flat-state specular reflections from the DMD window, DMD border structures, or other system surfaces near the DMD, such as prism or lens surfaces. If the numerical aperture exceeds the micromirror tilt angle, or if the projection numerical aperture angle is more than two degrees larger than the illumination numerical aperture angle (and vice versa), contrast degradation and objectionable artifacts in the display border and active area could occur.

6.5.2 Pupil Match

TI's optical and image quality specifications assume that the exit pupil of the illumination optics is nominally centered within 2° of the entrance pupil of the projection optics. Misalignment of pupils can create objectionable artifacts in the display border and active area, which may require additional system apertures to control, especially if the numerical aperture of the system exceeds the pixel tilt angle.

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6.5.3 Illumination Overfill

The active area of the device is surrounded by an aperture on the inside DMD window surface that masks structures of the DMD chip assembly from normal view and is sized to anticipate several optical operating conditions. Overfill light illuminating the window aperture can create artifacts from the edge of the window aperture opening and other surface anomalies that may be visible on the screen. The illumination optical system should be designed to limit a light flux incident anywhere on the window aperture from exceeding approximately 10% of the average flux level in the active area. Depending on the particular system's optical architecture, overfill light may have to be further reduced below the suggested 10% level to be acceptable.

6.6 Micromirror Array Temperature Calculation

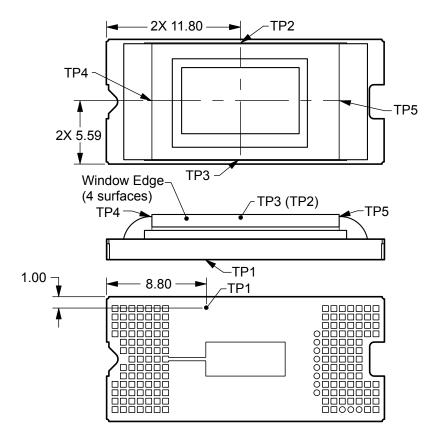


Figure 6-1. DMD Thermal Test Points

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Micromirror array temperature cannot be measured directly; therefore, it must be computed analytically from measurement points on the outside of the package, the package thermal resistance, the electrical power, and the illumination heat load. The relationship between the array temperature and the reference ceramic temperature (thermal test TC1/TP1 in Figure 6-1) is provided by the following equations:

$$T_{ARRAY} = T_{CERAMIC} + (Q_{ARRAY} \times R_{ARRAY-TO-CERAMIC})$$

$$Q_{ARRAY} = Q_{ELECTRICAL} + Q_{ILLUMINATION}$$

where

- T_{ARRAY} = Computed array temperature (°C)
- T_{CERAMIC} = Measured ceramic temperature (°C) (TP1 location)
- R_{ARRAY-TO-CERAMIC} = Thermal resistance of package specified in Figure 6-1 from array to ceramic TP1 (°C/Watt)
- Q_{ARRAY} = Total DMD power on the array (W) (electrical + absorbed)
- Q_{ELECTRICAL} = Nominal electrical power (W)
- Q_{INCIDENT} = Incident illumination optical power (W)
- Q_{ILLUMINATION} = (DMD average thermal absorptivity × Q_{INCIDENT}) (W)
- DMD average thermal absorptivity = 0.4

The electrical power dissipation of the DMD is variable and depends on the voltages, data rates, and operating frequencies. A nominal electrical power dissipation to use when calculating array temperature is 1.0 Watts. The absorbed power from the illumination source is variable and depends on the operating state of the micromirrors and the intensity of the light source. The equations shown above are valid for a single chip or multichip DMD system. It assumes an illumination distribution of 83.7% on the active array and 16.3% on the array border.

The sample calculation for a typical projection application is as follows:

```
Q_{\text{INCIDENT}} = 9.4 \text{W (measured)}
T_{\text{CERAMIC}} = 55.0^{\circ}\text{C (measured)}
Q_{\text{ELECTRICAL}} = 1.0 \text{W}
Q_{\text{ARRAY}} = 1.0 \text{W} + (0.40 \times 9.4 \text{W}) = 4.76 \text{W}
T_{\text{ARRAY}} = 55.0^{\circ}\text{C} + (4.76 \text{ W} \times 1.2^{\circ}\text{C/W}) = 60.7^{\circ}\text{C}
```

6.7 Micromirror Power Density Calculation

The calculation of the optical power density of the illumination on the DMD in the different wavelength bands uses the total measured optical power on the DMD, percent illumination overfill, area of the active array, and ratio of the spectrum in the wavelength band of interest to the total spectral optical power.

- ILL_{UV} = $[OP_{UV-RATIO} \times Q_{INCIDENT}] \times 1000 \text{ (mW/W)} \div A_{ILL} \text{ (mW/cm}^2)$
- ILL_{VIS} = [OP_{VIS-RATIO} × Q_{INCIDENT}] ÷ A_{ILL} (W/cm²)
- ILL_{IR} = [OP_{IR-RATIO} × Q_{INCIDENT}] × 1000 (mW/W) ÷ A_{ILL} (mW/cm²)
- ILL_{BLU} = [OP_{BLU-RATIO} × Q_{INCIDENT}] ÷ A_{ILL} (W/cm²)
- ILL_{BLU1} = [OP_{BLU1-RATIO} × Q_{INCIDENT}] ÷ A_{ILL} (W/cm²)



• $A_{ILL} = A_{ARRAY} \div (1 - OV_{ILL}) (cm^2)$

where:

- ILL_{UV} = UV illumination power density on the DMD (mW/cm²)
- ILL_{VIS} = VIS illumination power density on the DMD (W/cm²)
- ILL_{IR} = IR illumination power density on the DMD (mW/cm²)
- ILL_{BLU} = BLU illumination power density on the DMD (W/cm²)
- ILL_{BLU1} = BLU1 illumination power density on the DMD (W/cm²)
- A_{ILL} = illumination area on the DMD (cm²)
- Q_{INCIDENT} = total incident optical power on DMD (W) (measured)
- A_{ARRAY} = area of the array (cm²) (data sheet)
- OV_{ILL} = percent of total illumination on the DMD outside the array (%) (optical model)
- OP_{UV-RATIO} = ratio of the optical power for wavelengths <410nm to the total optical power in the illumination spectrum (spectral measurement)
- OP_{VIS-RATIO} = ratio of the optical power for wavelengths ≥410nm and ≤800nm to the total optical power in the illumination spectrum (spectral measurement)
- OP_{IR-RATIO} = ratio of the optical power for wavelengths >800nm to the total optical power in the illumination spectrum (spectral measurement)
- OP_{BLU-RATIO} = ratio of the optical power for wavelengths ≥410nm and ≤475nm to the total optical power in the illumination spectrum (spectral measurement)
- OP_{BLU1-RATIO} = ratio of the optical power for wavelengths ≥410nm and ≤445nm to the total optical power in the illumination spectrum (spectral measurement)

The illumination area varies and depends on the illumination overfill. The total illumination area on the DMD is the array area and the overfill area around the array. The optical model is used to determine the percent of the total illumination on the DMD that is outside the array (OV_{ILL}) and the percent of the total illumination that is on the active array. From these values, the illumination area (A_{ILL}) is calculated. The illumination is assumed to be uniform across the entire array.

From the measured illumination spectrum, the ratio of the optical power in the wavelength bands of interest to the total optical power is calculated.

Sample calculation:

 $Q_{INCIDENT} = 9.40 \text{ W (measured)}$

 $A_{ARRAY} = ((10.368 \text{ mm} \times 5.832 \text{ mm}) \div 100 \text{cm}^2/\text{mm}^2) = 0.6047 \text{ cm}^2 \text{ (data sheet)}$

OV_{ILL} = 16.3% (optical model)

OP_{UV-RATIO} = 0.00021 (spectral measurement)

OP_{VIS-RATIO} = 0.99977 (spectral measurement)

 $OP_{IR-RATIO} = 0.00002$ (spectral measurement) $OP_{BLU-RATIO} = 0.28100$ (spectral measurement)

OP_{BLU1-RATIO} = 0.03200 (spectral measurement)



$$\begin{split} &A_{ILL} = 0.6047 \text{ cm}^2 \div (1 - 0.163) = 0.7224 \text{ cm}^2 \\ &ILL_{UV} = [0.00021 \times 9.40 \text{ W}] \times 1000 \text{mW/W} \div 0.7224 \text{ cm}^2 = 2.732 \text{ mW/cm}^2 \\ &ILL_{VIS} = [0.99977 \times 9.40 \text{ W}] \div 0.7224 \text{ cm}^2 = 13.01 \text{ mW/cm}^2 \\ &ILL_{IR} = [0.00002 \times 9.40 \text{ W}] \times 1000 \text{mW/W} \div 0.7224 \text{ cm}^2 = 0.260 \text{ mW/cm}^2 \\ &ILL_{BLU} = [0.28100 \times 9.40 \text{ W}] \div 0.7224 \text{ cm}^2 = 3.66 \text{ mW/cm}^2 \\ &ILL_{BLU1} = [0.03200 \times 9.40 \text{ W}] \div 0.7224 \text{ cm}^2 = 0.42 \text{ mW/cm}^2 \end{split}$$

6.8 Micromirror Landed-On/Landed-Off Duty Cycle

6.8.1 Definition of Micromirror Landed-On/Landed-Off Duty Cycle

The micromirror landed-on/landed-off duty cycle (landed duty cycle) denotes the percentage of time that an individual micromirror is landed in the ON state versus the amount of time the same micromirror is landed in the OFF state.

For example, a landed duty cycle of 100/0 indicates that the referenced pixel is in the ON state 100% of the time (and in the OFF state 0% of the time); whereas 0/100 would indicate that the pixel is in the OFF state 100% of the time. Likewise, 50/50 indicates that the pixel is ON for 50% of the time (and OFF for 50% of the time).

Note that when assessing the landed duty cycle, the time spent switching from one state (ON or OFF) to the other state (OFF or ON) is considered negligible and is thus ignored.

Since a micromirror can only be landed in one state or the other (ON or OFF), the two numbers (percentages) always add to 100.

6.8.2 Landed Duty Cycle and Useful Life of the DMD

Knowing the long-term average landed duty cycle (of the end product or application) is important because subjecting all (or a portion) of the DMD micromirror array (also called the active array) to an asymmetric landed duty cycle for a prolonged period of time can reduce the DMD's useful life.

Note that it is the symmetry/asymmetry of the landed duty cycle that is of relevance. The symmetry of the landed duty cycle is determined by how close the two numbers (percentages) are to being equal. For example, a landed duty cycle of 50/50 is perfectly symmetrical, whereas a landed duty cycle of 100/0 or 0/100 is perfectly asymmetrical.

6.8.3 Landed Duty Cycle and Operational DMD Temperature

Operational DMD temperature and landed duty cycle interact to affect DMD useful life, and this interaction can be exploited to reduce the impact that an asymmetrical landed duty cycle has on the DMD useful life. This is quantified in the derating curve shown in Figure 5-1. The importance of this curve is that:

- All points along this curve represent the same useful life.
- All points above this curve represent a lower useful life (and the further away from the curve, the lower the useful life).
- All points below this curve represent a higher useful life (and the further away from the curve, the higher the useful life).

This curve specifies the maximum operating DMD temperature that the DMD should be operated at for a given long-term average landed duty cycle.

6.8.4 Estimating the Long-Term Average Landed Duty Cycle of a Product or Application

During a given period of time, the landed duty cycle of a given pixel follows from the image content being displayed by that pixel.



For example, in the simplest case, when displaying pure-white on a given pixel for a given time period, that pixel operates under a 100/0 landed duty cycle during that time period. Likewise, when displaying pure-black, the pixel operates under a 0/100 landed duty cycle.

Between the two extremes (ignoring for the moment color and any image processing that may be applied to an incoming image), the landed duty cycle tracks one-to-one with the gray scale value, as shown in Table 6-1.

Table 6-1. Grayscale Value and Landed Duty Cycle

GRAYSCALE VALUE	LANDED DUTY CYCLE
0%	0/100
10%	10/90
20%	20/80
30%	30/70
40%	40/60
50%	50/50
60%	60/40
70%	70/30
80%	80/20
90%	90/10
100%	100/0

Accounting for color rendition (but still ignoring image processing) requires knowing both the color intensity (from 0% to 100%) for each constituent primary color (red, green, and/or blue) for the given pixel as well as the color cycle time for each primary color, where "color cycle time" is the total percentage of the frame time that a given primary must be displayed in order to achieve the desired white point.

Use Equation 1 to calculate the landed duty cycle of a given pixel during a given time period.

where

- Red Cycle % represents the percentage of the frame time that red is displayed to achieve the desired white point
- Green Cycle % represents the percentage of the frame time that green is displayed to achieve the desired white point
- Blue Cycle % represents the percentage of the frame time that blue is displayed to achieve the desired white point

For example, assume that the red, green, and blue color cycle times are 30%, 50%, and 20% respectively (in order to achieve the desired white point), then the landed duty cycle for various combinations of red, green, blue color intensities would be as shown in Table 6-2 and Table 6-3.

Table 6-2. Example Landed Duty Cycle for Full-Color, Color Percentage

CYCLE PERCENTAGE					
GREEN	BLUE	RED			
50%	20%	30%			

Table 6-3. Example Landed Duty Cycle for Full-Color

s	LANDED DUTY		
GREEN	BLUE	RED	CYCLE
0%	0%	0%	0/100



Table 6-3. Example Landed Duty Cycle for Full-Color (continued)

S	CALE VALUE	·	LANDED DUTY
GREEN	BLUE	RED	CYCLE
100%	0%	0%	50/50
0%	100%	0%	20/80
0%	0%	100%	30/70
12%	0%	0%	6/94
0%	35%	0%	7/93
0%	0%	60%	18/82
100%	100%	0%	70/30
0%	100%	100%	50/50
100%	0%	100%	80/20
12%	35%	0%	13/87
0%	35%	60%	25/75
12%	0%	60%	24/76
100%	100%	100%	100/0

The last factor to account for in estimating the landed duty cycle is any applied image processing. Within the controller, the gamma function affects the landed duty cycle.

Gamma is a power function of the form $Output_Level = A \times Input_Level^{Gamma}$, where A is a scaling factor that is typically set to 1.

In the controller, gamma is applied to the incoming image data on a pixel-by-pixel basis. A typical gamma factor is 2.2, which transforms the incoming data as shown in Figure 6-2.

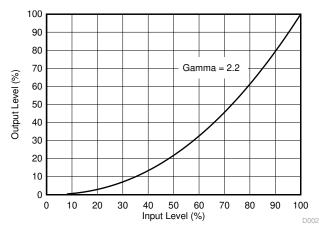


Figure 6-2. Example of Gamma = 2.2

From Figure 6-2, if the grayscale value of a given input pixel is 40% (before gamma is applied), then the grayscale value is 13% after gamma is applied. Therefore, it can be seen that since gamma has a direct impact displayed grayscale level of a pixel, it also has a direct impact on the landed duty cycle of a pixel.

Consideration must also be given to any image processing that occurs before the controller.

7 Application and Implementation

Note

Information in the following applications sections is not part of the TI component specification, and TI does not warrant its accuracy or completeness. TI's customers are responsible for determining suitability of components for their purposes, as well as validating and testing their design implementation to confirm system functionality.

7.1 Application Information

DMDs are spatial light modulators that reflect incoming light from an illumination source to one of two directions, with the primary direction being into a projection or collection optic. Each application is derived primarily from the optical architecture of the system and the format of the data coming into the DLPC8444 controller. The high tilt pixel in the bottom-illuminated DMD increases brightness performance and enables a smaller system footprint for thickness-constrained applications. Typical applications using the DLP472NP include mobile smart TVs and digital signage.

DMD power-up and power-down sequencing is strictly controlled by the DLPA3085 or DLPA3082 . Refer to Section 8 for power-up and power-down specifications. To ensure reliable operation, the DLP472NP DMD must always be used with the DLPC8444 controller and a DLPA3085 or DLPA3082 PMIC.

7.2 Typical Application

The DLP472NP DMD, combined with DLPC8444 digital controller and a power management device, provides full 1080p FHD resolution for bright, colorful display applications. See Figure 7-1, which shows the system components needed along with the LED configuration of the DLP 0.47" 1080p FHD chipset. The components include the DLP472NP DMD, the DLPC8444 display controller, and the DLPA3085 or DLPA3082 PMIC and LED driver.

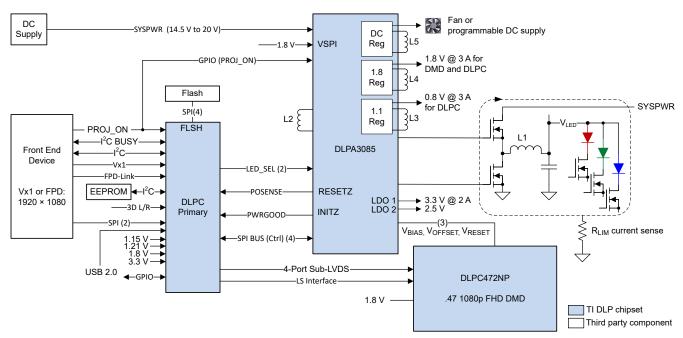


Figure 7-1. Typical 1080p FHD LED Application Diagram



7.2.1 Design Requirements

Other core components of the display system include an illumination source, an optical engine for the illumination and projection optics, other electrical and mechanical components, and software. The type of illumination used and the desired brightness have a major effect on the overall system design and size.

The display system uses the DLP472NP as the core imaging device and contains a 0.47-inch array of micromirrors. The DLPC8444 controller is the digital interface between the DMD and the rest of the system, taking digital input from the front-end receiver and driving the DMD over a high-speed interface. The DLPA3085 or DLPA3082 PMIC serves as a voltage regulator for the DMD, controller, and LED illumination functionality.

7.2.2 Detailed Design Procedure

For a complete DLP system, an optical module or light engine is required that contains the DLP472NP DMD, associated illumination sources, optical elements, and necessary mechanical components.

To ensure reliable operation, the DMD must always be used with the DLPC8444 display controller and the DLPA3085 or DLPA3082 PMIC driver.

7.2.3 Application Curve

The typical LED-current-to-luminance relationship when LED illumination is used is shown in Figure 7-2.

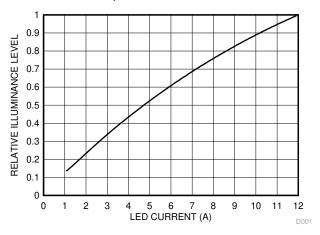


Figure 7-2. Luminance vs Current

7.3 Temperature Sensor Diode

The software application provides functions to configure the TMP411 to read the DLP472NP DMD temperature sensor diode. Use this data to incorporate additional functionality in the overall system design, such as adjusting illumination, fan speeds, and so on. All communication between the TMP411 and the DLPC8444 controller is completed using the I²C interface. The TMP411 connects to the DMD through the pins outlined in Section 4.



8 Power Supply Recommendations

The following power supplies are all required to operate the DMD:

- V_{SS}
- V_{BIAS}
- V_{DD}
- V_{DDI}
- V_{OFFSET}
- V_{RESET}

DMD power-up and power-down sequencing is strictly controlled by the DLP display controller.

CAUTION

For reliable operation of the DMD, the following power supply sequencing requirements must be followed. Failure to adhere to any of the prescribed power-up and power-down requirements may affect device reliability. See the DMD power supply sequencing requirements in Figure 8-1.

V_{BIAS}, V_{DD}, V_{DDI}, V_{OEFSET}, and V_{RESET} power supplies must be coordinated during power-up and power-down operations. Failure to meet any of the below requirements result in a significant reduction in the DMD reliability and lifetime. Common ground V_{SS} must also be connected.

Table 8-1. Power Supply Sequence Requirements

SYMBOL	PARAMETER	DESCRIPTION	MIN	TYP	MAX	UNIT
t _{DELAY}	Delay requirement	from V _{OFFSET} power up to V _{BIAS} power up	2			ms
V _{OFFSET}	Supply voltage level	at beginning of power-up sequence delay ⁽¹⁾			6	V
V _{BIAS}	Supply voltage level	at end of power-up sequence delay ⁽¹⁾			6	V

⁽¹⁾ See Figure 8-1, Power-Up Sequence Delay Requirement.

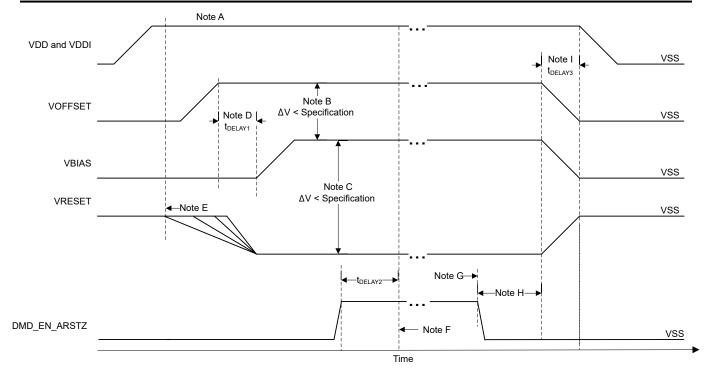
8.1 DMD Power Supply Power-Up Procedure

- During power-up, V_{DD} and V_{DDI} must always start and settle before V_{OFFSET} plus Delay1 specified in Table 8-2, V_{BIAS}, and V_{RESET} voltages are applied to the DMD.
- During power-up, it is a strict requirement that the voltage difference between V_{BIAS} and V_{OFFSET} must be within the specified limit shown in Section 5.4.
- During power-up, there is no requirement for the relative timing of V_{RESET} with respect to V_{BIAS}.
- Power supply slew rates during power-up are flexible, provided that the transient voltage levels follow the requirements specified in Section 5.1, in Section 5.4, and in Figure 8-1.
- During power-up, LVCMOS input pins must not be driven high until after V_{DD} have settled at operating voltages listed in Section 5.4.

8.2 DMD Power Supply Power-Down Procedure

- During power-down, V_{DD} and V_{DDI} must be supplied until after V_{BIAS}, V_{RESET}, and V_{OFFSET} are discharged to within the specified limit of ground. See Table 8-2.
- During power-down, it is a strict requirement that the voltage difference between V_{BIAS} and V_{OFFSET} must be within the specified limit shown in Section 5.4.
- During power-down, there is no requirement for the relative timing of V_{RESET} with respect to V_{BIAS}.
- Power supply slew rates during power-down are flexible, provided that the transient voltage levels follow the requirements specified in Section 5.1, in Section 5.4, and in Figure 8-1.
- During power-down, LVCMOS input pins must be less than specified in Section 5.4.





- A. See Section 4 for the Pin Functions Table.
- B. To prevent excess current, the supply voltage difference |V_{OFFSET} V_{BIAS}| must be less than the specified limit in Section 5.4.
- C. To prevent excess current, the supply difference $|V_{BIAS} V_{RESET}|$ must be less than the specified limit in Section 5.4.
- D. V_{BIAS} should power up after V_{OFFSET} has powered up, per the Delay1 specification in Table 8-2.
- $\hbox{E.}\quad \hbox{DLP controller software initiates the global V_{BIAS} command.}$
- F. After the DMD micromirror park sequence is complete, the DLP controller software initiates a hardware power-down that activates DMD_EN_ARSTZ and disables V_{BIAS}, V_{RESET}, and V_{OFFSET}.
- G. Under power-loss conditions where emergency DMD micromirror park procedures are being enacted by the DLP controller hardware DMD_EN_ARSTZ will go low.
- H. V_{DD} must remain high until after V_{OFFSET}, V_{BIAS}, and V_{RESET} go low, per Delay2 specification in Table 8-2.
- I. To prevent excess current, the supply voltage delta $|V_{DDI} V_{DD}|$ must be less than the specified limit in Section 5.4.

Figure 8-1. DMD Power Supply Requirements

Table 8-2. DMD Power-Supply Requirements

PARAMETER	DESCRIPTION	MIN	NOM	MAX	UNIT
Delay1 ⁽¹⁾	Delay from V_{OFFSET} settled at recommended operating voltage to V_{BIAS} and V_{RESET} power up	1	2		ms
Delay2 ⁽¹⁾	Delay V_{DD} must be held high from V_{OFFSET} , V_{BIAS} , and V_{RESET} powering down.	50			μs

(1) See Figure 8-1.



9 Layout

9.1 Layout Guidelines

The DLP472NP DMD connects to a PCB or a flex circuit using an interposer. For additional layout guidelines regarding length matching and impedance, see the DLPC8444 controller data sheet. For a detailed layout example, refer to the layout design files. Some layout guidelines for routing to the DLP472NP DMD are:

- Match lengths for the LS_WDATA and LS_CLK signals, as specified in the DLPC8444 controller data sheet.
- Match lengths for the HS bus differential signals as specified in the DLPC8444 controller data sheet.
- Minimize vias, layer changes, and turns for the HS bus signals. Refer to Figure 9-1.
- Supply capacitance needs can vary per design. Refer to the layout design file for a general guideline.
 Supplies need to be verified on the design to ensure all supplies are operating in the recommended operating range at the DMD.



9.2 Layout Example

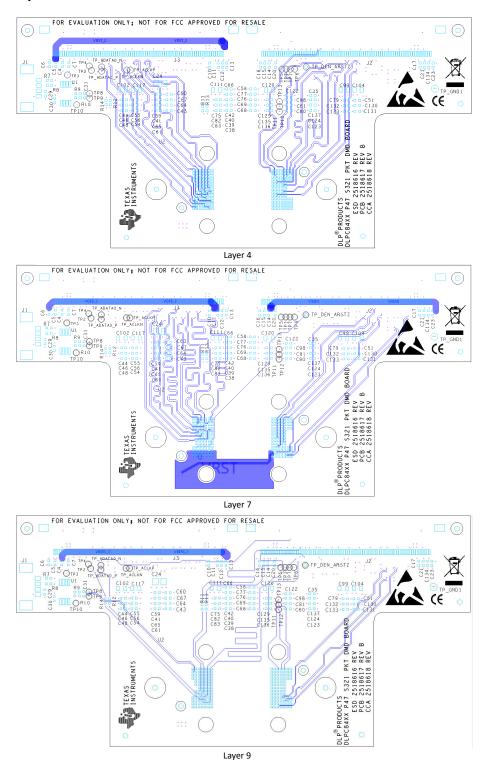


Figure 9-1. Routing Example



10 Device and Documentation Support

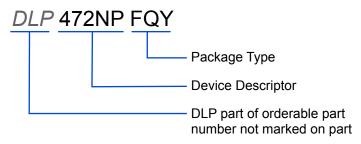
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10.2 Device Support

10.2.1 Device Nomenclature

Figure 10-1. Part Number Description

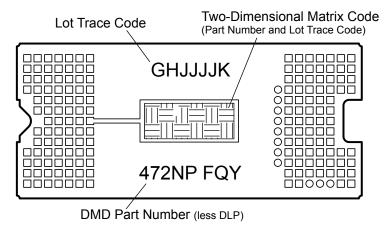


10.2.2 Device Markings

The device marking includes both human-readable information and a 2-dimensional matrix code. The humanreadable information is described in Figure 10-2 and includes the legible character string GHJJJJK 472NPFQY. GHJJJJK is the lot trace code and 472NPFQY is the device marking.

Example: GHJJJJK DLP472NPFQY

Figure 10-2. DMD Marking Locations



10.3 Documentation Support

10.3.1 Related Documentation

The following documents contain additional information related to the chipset components used with the DMD.

- DLPC84x4 High-Resolution Controllers
- DLPA3085 PMIC and High-Current LED Driver IC Data Sheet
- DLPA3082 PMIC IC Data Sheet

10.4 Receiving Notification of Documentation Updates

To receive notification of documentation updates, navigate to the device product folder on ti.com. Click on *Notifications* to register and receive a weekly digest of any product information that has changed. For change details, review the revision history included in any revised document.

10.5 Trademarks

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10.6 Electrostatic Discharge Caution



This integrated circuit can be damaged by ESD. Texas Instruments recommends that all integrated circuits be handled with appropriate precautions. Failure to observe proper handling and installation procedures can cause damage.

ESD damage can range from subtle performance degradation to complete device failure. Precision integrated circuits may be more susceptible to damage because very small parametric changes could cause the device not to meet its published specifications.

10.7 Glossary

TI Glossary

This glossary lists and explains terms, acronyms, and definitions.

11 Revision History

DATE	REVISION	NOTES				
August 2025	*	Initial Release				

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DLPS258 - AUGUST 2025



12 Mechanical, Packaging, and Orderable Information

The following pages include mechanical, packaging, and orderable information. This information is the most current data available for the designated devices. This data is subject to change without notice and revision of this document. For browser-based versions of this data sheet, refer to the left-hand navigation.

www.ti.com 24-Aug-2025

PACKAGING INFORMATION

Orderable part number	Status	Material type	Package Pins	Package qty Carrier	RoHS (3)	Lead finish/ Ball material	MSL rating/ Peak reflow	Op temp (°C)	Part marking (6)
DLP472NPFQY	Active	Production	CLGA (FQY) 174	80 JEDEC TRAY (5+1)	In-Work	NI/AU	N/A for Pkg Type	0 to 70	

⁽¹⁾ Status: For more details on status, see our product life cycle.

- (3) RoHS values: Yes, No, RoHS Exempt. See the TI RoHS Statement for additional information and value definition.
- (4) Lead finish/Ball material: Parts may have multiple material finish options. Finish options are separated by a vertical ruled line. Lead finish/Ball material values may wrap to two lines if the finish value exceeds the maximum column width.
- (5) MSL rating/Peak reflow: The moisture sensitivity level ratings and peak solder (reflow) temperatures. In the event that a part has multiple moisture sensitivity ratings, only the lowest level per JEDEC standards is shown. Refer to the shipping label for the actual reflow temperature that will be used to mount the part to the printed circuit board.
- (6) Part marking: There may be an additional marking, which relates to the logo, the lot trace code information, or the environmental category of the part.

Multiple part markings will be inside parentheses. Only one part marking contained in parentheses and separated by a "~" will appear on a part. If a line is indented then it is a continuation of the previous line and the two combined represent the entire part marking for that device.

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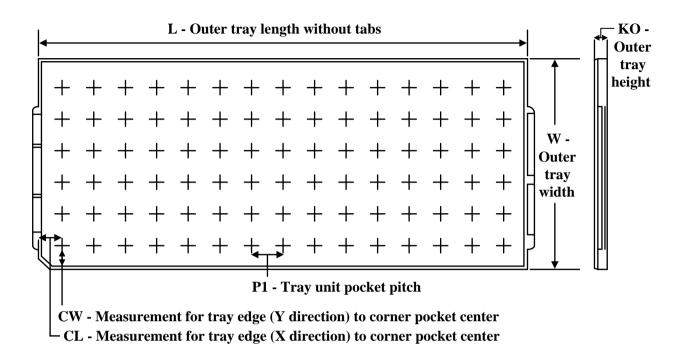
In no event shall TI's liability arising out of such information exceed the total purchase price of the TI part(s) at issue in this document sold by TI to Customer on an annual basis.

⁽²⁾ Material type: When designated, preproduction parts are prototypes/experimental devices, and are not yet approved or released for full production. Testing and final process, including without limitation quality assurance, reliability performance testing, and/or process qualification, may not yet be complete, and this item is subject to further changes or possible discontinuation. If available for ordering, purchases will be subject to an additional waiver at checkout, and are intended for early internal evaluation purposes only. These items are sold without warranties of any kind.



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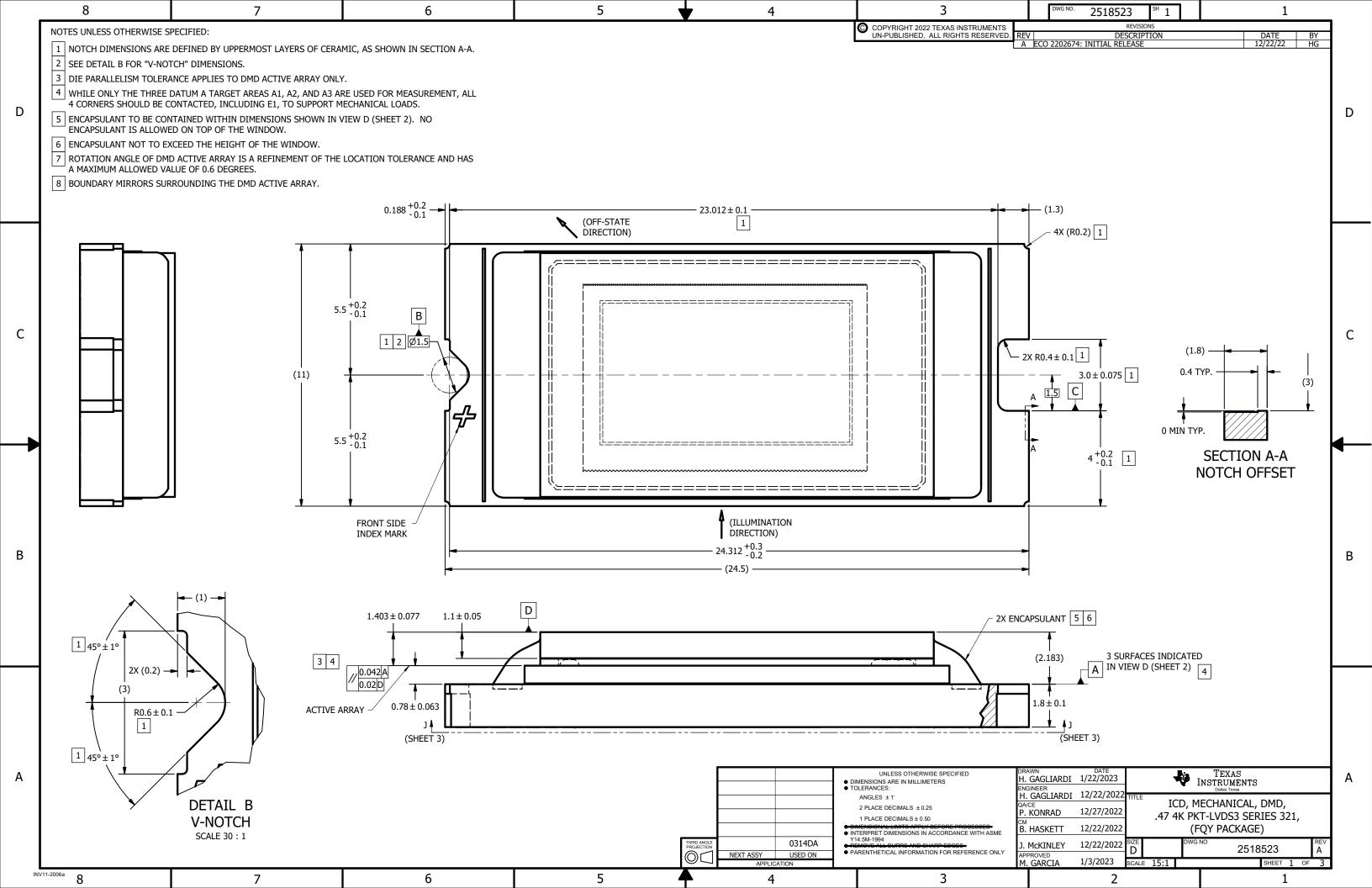
TRAY

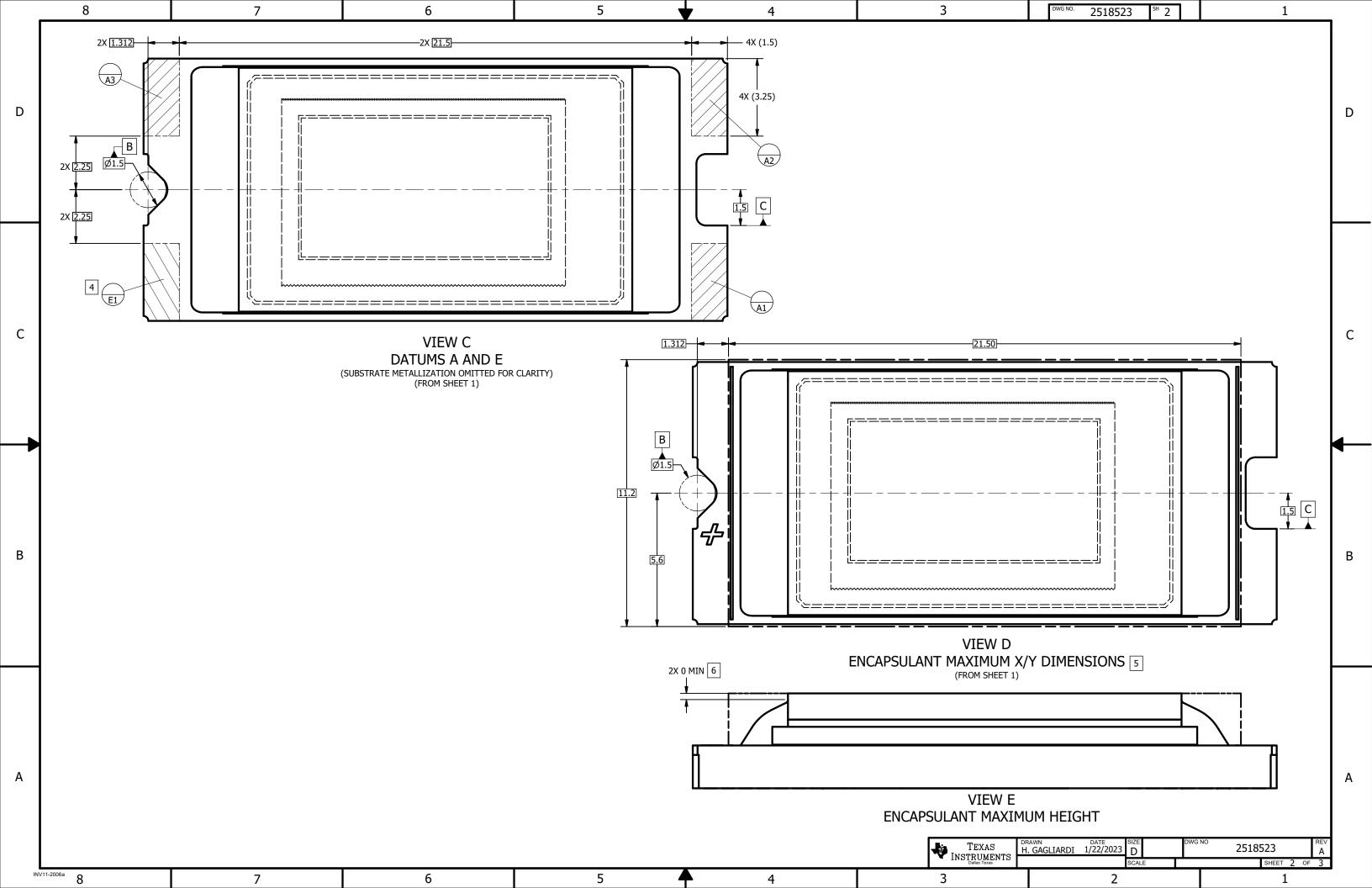


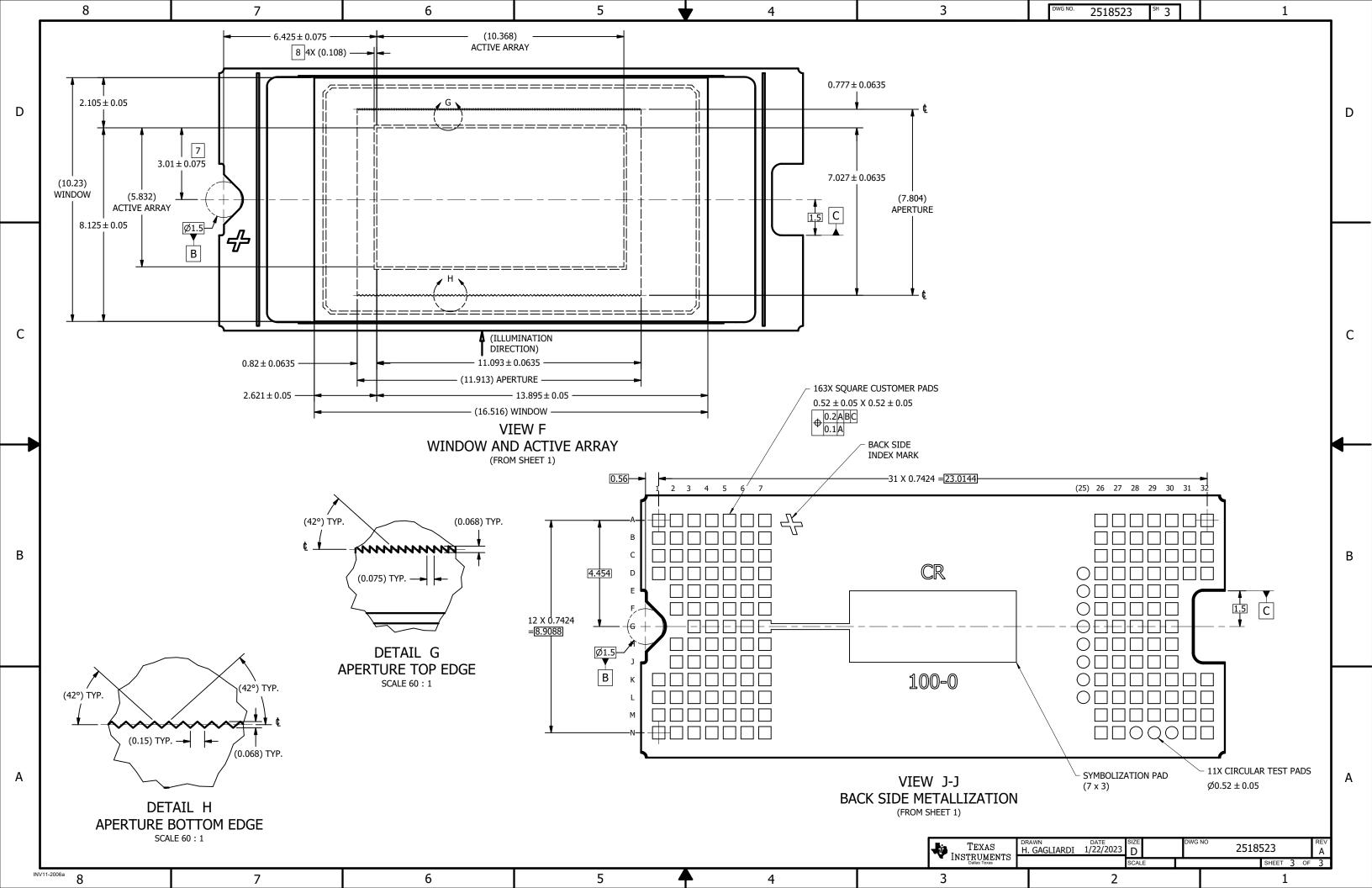
Chamfer on Tray corner indicates Pin 1 orientation of packed units.

*All dimensions are nominal

Device	Package Name	Package Type	Pins	SPQ	Unit array matrix	Max temperature (°C)	L (mm)	W (mm)	Κ0 (μm)	P1 (mm)	CL (mm)	CW (mm)
DLP472NPFQY	FQY	CLGA	174	80	8 x 10	150	315	135.9	12190	28	31.5	15.45







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